

Customer No.: 31561
Application No.: 10/708,707
Docket No.: 10789-US-PA

AMENDMENTS

FOR THE CLAIMS

Claim 1. (currently amended) A wafer bumping process, comprising the steps of:
providing a wafer, said wafer comprising a plurality of bonding pads and a passivation layer covering a surface of said wafer and exposing said bonding pads;

forming a first under bump metallurgy layer covering said passivation layer and said bonding pads;

forming a first patterned photoresist layer on said first under bump metallurgy layer, said first patterned photoresist layer comprising a plurality of first openings corresponding to said bonding pads and exposing a portion of said first under bump metallurgy layer;

forming a second under bump metallurgy layer within said first openings;

forming a second patterned photoresist layer on said first patterned photoresist layer, said second patterned photoresist layer comprising a plurality of second openings, said second openings being larger than said first openings to expose a portion of said second under bump metallurgy layer;

filling said second openings with a solder material, wherein the solder material covers said exposed portion of said second under bump metallurgy layer;

reflowing said solder material to form a plurality of solder bumps;

after reflowing said solder material, removing said second patterned photoresist

Customer No.: 31561
Application No.: 10/708,707
Docket No.: 10789-US-PA

layer and said first patterned photoresist layer to expose a portion of said first under bump metallurgy layer; and

removing said exposed portion of said first under bump metallurgy layer.

Claim 2. (original) The wafer bumping process of claim 1, wherein the step of filling said solder material includes printing.

Claim 3. (original) The wafer bumping process of claim 1, wherein the step of filling said solder material includes electroplating.

Claim 4. (original) The wafer bumping process of claim 1, wherein sidewalls of said second openings are slanting and said second openings expose said portion of said second under bump metallurgy layer.

Claim 5. (original) The wafer bumping process of claim 4, wherein said second openings taper towards said second under bump metallurgy layer within said first openings to expose said portion of said second under bump metallurgy layer.

Claim 6. (original) The wafer bumping process of claim 1, wherein said the step of forming first under bump metallurgy layer includes sputtering deposition.

Claim 7. (original) The wafer bumping process of claim 1, wherein the step of forming second under bump metallurgy layer includes electroplating.

Claim 8. (original) The wafer bumping process of claim 1, wherein a material of said first under bump metallurgy layer is selected from the group of materials consisting of Cr, Ti, Ti-W alloy, Cu, Ni, Cr-Cu alloy, Ni-V alloy, Ni-Au alloy, and Al.

Claim 9. (original) The wafer bumping process of claim 1, wherein a thickness of

Customer No.: 31561
Application No.: 10/708,707
Docket No.: 10789-US-PA

the said second under bump metallurgy layer is about 30-75 μ m.

Claim 10. (original) The wafer bumping process of claim 1, wherein a material of said second under bump metallurgy layer having a melting point larger than a melting point of said solder material.

Claim 11. (original) The wafer bumping process of claim 10, wherein a material of said second under bump metallurgy layer includes Cu.

Claim 12. (original) The wafer bumping process of claim 10, wherein a material of said second under bump metallurgy layer includes Ni.

Claim 13. (original) The wafer bumping process of claim 1, wherein a material of said solder material includes a Sn-Pb alloy.

Claim 14. (original) The wafer bumping process of claim 1, wherein a material of said solder material includes a Sn-Ag-Cu alloy.

Claim 15. (original) The wafer bumping process of claim 1, wherein a material of said solder material includes a high lead solder.

Claim 16. (currently amended) A structure of bumps comprising:

a substrate having at least an active surface;

a plurality of bonding pads formed on the active surface;

a passivation layer formed over the active surface of the substrate, wherein portions of the bonding pads are exposed by the passivation layer;

a first under bump metallurgy layer formed on the exposed portions of the bonding pads;

Customer No.: 31561
Application No.: 10/708,707
Docket No.: 10789-US-PA

a second under bump metallurgy layer formed on the first under bump metallurgy layer; and

a plurality of solder bumps formed on the second under bump metallurgy layer without covering sidewalls of the second under bump metallurgy layer, wherein a melting point of the solder bumps is lower than a melting point of the second under bump metallurgy layer.

Claim 17. (original) The structure of claim 16, wherein a material of the second under bump metallurgy layer includes Cu.

Claim 18. (original) The structure of claim 16, wherein the second under bump metallurgy layer is a nickel layer.

Claim 19. (original) The structure of claim 16, wherein a thickness of the second under bump metallurgy layer is larger than that of the first under bump metallurgy layer.

Claim 20. (original) The structure of claim 16, wherein a thickness of the second under bump metallurgy is about 30-75 μm .

Claim 21. (original) The structure of claim 16, wherein the first under bump metallurgy is composed of Ti, Ni-V alloy and Cu and directly formed on the exposed portions of the bonding pads.